

SW Test Workshop

Semiconductor Wafer Test Workshop June 7 - 10, 2015 | San Diego, California

Determining Probe's Maximum Allowable Current



FORMFACTOR INC.

Amer Cassier, Richard Folwarski (Qualcomm Technologies Inc.) Jarek Kister, Amy Leong (FormFactor)

Qualcomm is a trademark of Qualcomm Incorporated, registered in the United States and other countries, used with permission. Other product and brand names may be trademarks or registered trademarks of their respective owners.



- ISMI CCC Spec vs. what wafer test engineer needs to know
- Introducing <u>Maximum Allowable Current (MAC) concept</u>
- Method for finding singular MAC value
- Confirmation of MAC performance in repeatable loading
- Relationship between MAC and CCC
- MAC vs. current pulse width
- Ways to minimize transient currents in wafer test
- Conclusions

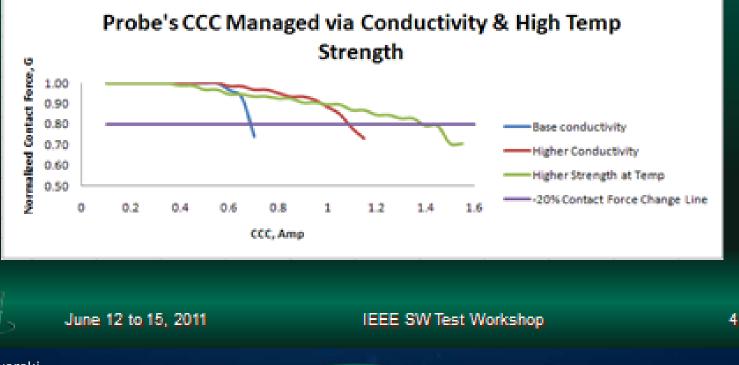
Cassier, Folwarski, Kister, Leong

Definition of CCC

- CCC = Current which results in a 20% contact force reduction
 - Below plot typical of SEMI-defined methodology

June 7-10, 2015

- CCC modulated by several variables
 - Here, improvement achieved through probe material conductivity (electrical and thermal) and high temperature strength increase

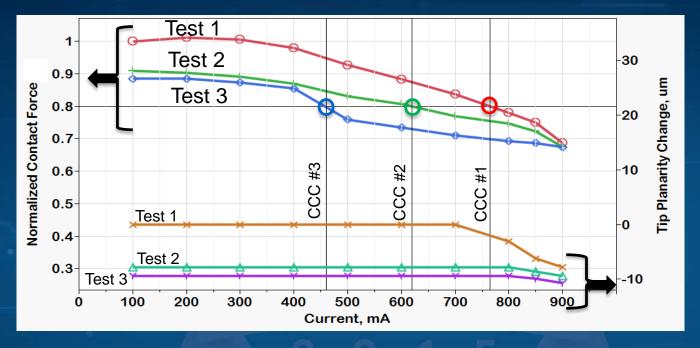


25TH ANNIVERSARY

SW Test Workshop

Cassier, Folwarski Kister, Leong

CCC-level Current Damages Probes



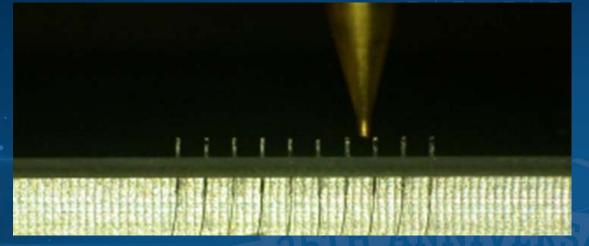
- The same probe tested for CCC three times shows diminishing actual CCC and Tip planarity, ~150mA reduction per test
- Probes cannot sustain CCC-level current due to loss of planarity and contact force
- CCC spec causes many misunderstandings between users and probe card suppliers
 - Why can't I use CCC spec for current clamp setting?
 - Why does probe card contact performance degrade over time after exposure to CCC?

Cassier, Kister, Leong

Probe ISMI-CCC Spec Does not Define Current that Probe Could Carry After Multiple Exposure in Production

- Disparity between what test engineer needs to know about the probe and what ISMI-CCC spec defines:
 - Test engineer asks for maximum current that can be carried by the probe thousands of times without changing probe's performance (planarity, alignment, contact force, CRES)
 - ISMI-CCC test itself causes a permanent damage to the probe probe is deformed and contact force lowered by 20% after one current event
- Methodology is needed to measure <u>Maximum Allowable</u> <u>Current that can be applied over and over throughout product</u> life time
 - To help with setting power supply current clamp in tester program



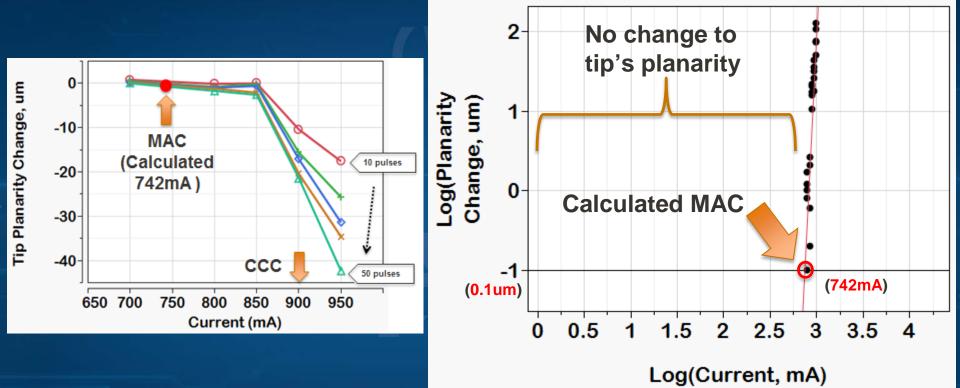


Contact Force, Planarity Program mable Power Supply

- Use probe tip's planarity change in response to current pulses as a proxy for defining probe's <u>Maximum Allowable Current (MAC)</u>
- Each probe is tested at a unique current level in increasing number of pulses, (1 min On /1sec off) representing real life test scenario

Cassier, Folwarski, Kister, Leong

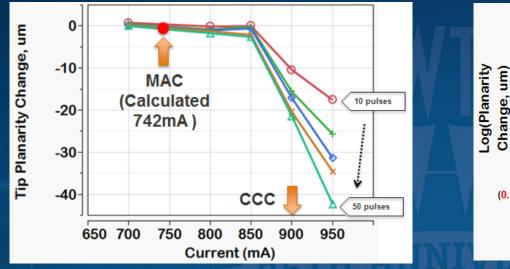
<u>Maximum Allowable Current</u> Calculation of MAC value

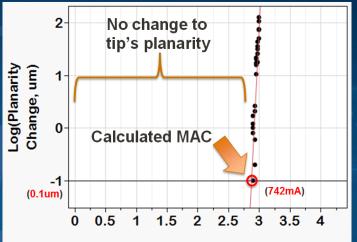


- Plotting Log of planarity change vs. Log of current (use linear scale) allows for linearization of otherwise asymptotic curve
- Finding best-fit line equation to the data is easy and used to calculate MAC, in this case MAC=10^(2.8705)=742 mA for planarity change =0.1um

Cassier, Folwarski, Kister, Leong

Confirmation of MAC concept, Stable Probe Tip Planarity after 35k MAC pulses

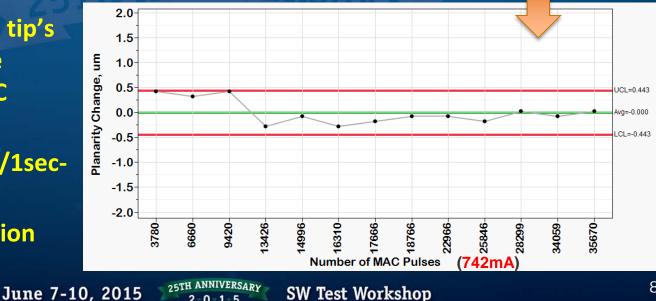




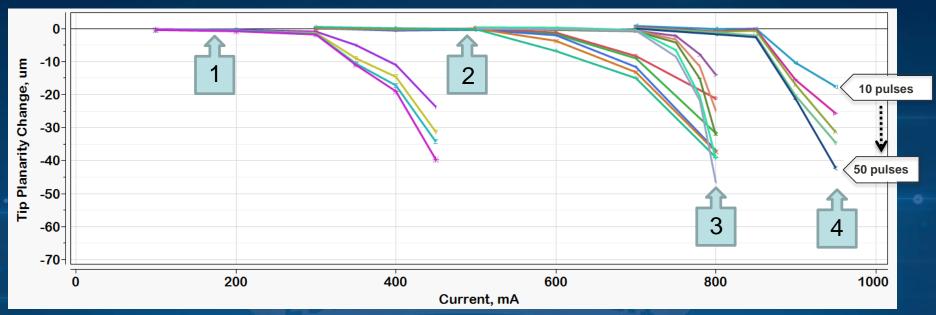
Log(Current, mA)

- No change to probe tip's 0 planarity during the performed 35k MAC (742mA) pulses
- Each pulse 1min-on/1sec-0 off
- 75um probe deflection 0

Cassier, Folwarski Kister, Leong



MAC vs. CCC for a Range of Probes



 MAC/CCC Ratio is not a constant, is probe architecture dependent

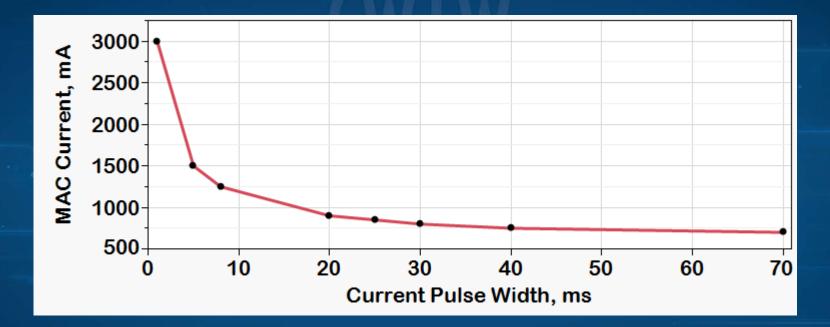
Probe	ISMI CCC, mA	MAC, mA	MAC/CCC
	450	278	~0.6
2	800	478	~0.6
3	800	637	~0.8
4	900	742	~0.8

Cassier, Folwarski, Kister, Leong

June 7-10, 2015 2-0 1-5

💱 🚺 SW Test Workshop

MAC vs. Current Pulse Width for a 900mA CCC/742mA MAC probe



- For current pulse >=70mS the MAC value does not change
- Practical current pulses used in wafer tests exceed 70mS, therefore, shorter pulses cannot be used to "increase" MAC
- Ultra short pulses (<1 msec) can help "transient current" management

Cassier, Folwarski, Kister, Leong

June 7-10, 2015 2-0-1-5 SW Test Workshop

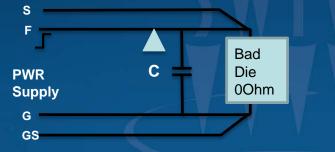
Impact of Test and Power Supply on Probes

- Significant static and transient currents can happen during wafer test due to electric shorts in faulty chips
 - >2A current have been experienced
- Faulty devices must be screened out at lower voltage setting with current clamp limits set <=MAC at the begining of the wafer test
 - Full voltage and higher clamp limits are applied only to confirmed good die
- Management of power supply is needed in the test program to protect probes:
 - Current range, clamp limits and the response time -> example 1
 - Power supply slew rate (dv/dt) and transient current magnitude -> example 2

Cassier, Folwarski, Kister, Leong

Example 1: Current Profile and Clamp Response Time

• Test Case: Clamp response time for the same power supply under 100mV step into a shorted device (Vdd shorted to Vss) at different current



- Current clamp is effective in limiting static current; however, its response time is not fast enough to completely limit the transient current
- To protect probes from damage, transient current magnitude and duration must be limited
 - Select lower current range of the power supply to reduce transient current spikes

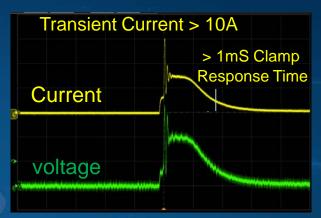
June 7-10, 2015

• Reduce clamp response time by switching off large capacitance

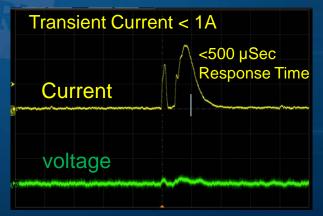
Cassier, Folwarski Kister, Leong

range

Higher Current Range



Lower Current Range

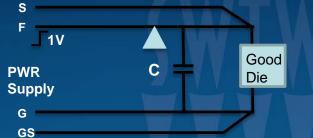


SW Test Workshop

Example 2: Slew Rate Effect on Transient Currents

• Test Case: Transient current response versus Voltage slew rate. Same power supply.

No current clamp



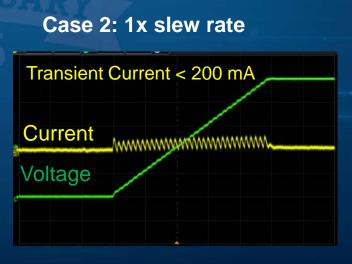
• Case 1 :

- Fast Slew Rate 50 x
- > 3A peak current within 1 milli-second

• Case 2 :

- Slow slew rate 1x (digitally controlled in steps)
- < 200mA peak current</p>
- Slower slew rate minimizes magnitude of current surge to protect probes; however, it can have a small impact on test time
- Actual current going through the probes depends on device and capacitor impedance





Conclusions

- The Maximum Allowable Current (MAC) represents actual current that probe can safely deliver, a more reliable specification than CCC
- MAC is defined as current level at which probe will not change its planarity or cause permanent damage in repeated use
 - Duty cycle representative of test time and prober indexing time
- MAC is lower than CCC, however the MAC/CCC ratio is not a constant number varies based on probe architecture
- For current pulse shorter than 1 millisecond, a probe can sustain significantly higher current than MAC without damage
- Current clamp is effective in limiting static current; however, its response time is not fast enough to completely limit the transient current
- Slower power supply slew rate minimizes magnitude of transient current to protect probes